

Radiation Effects Study of Components Operated at Cryogenic Temperature and Future Generations Semiconductor Devices

60 Mev Proton and Gamma Irradiation Effects on NO and RNO Deep Submicron MOSFETs Fabricated in IMEC's 0.13 μm CMOS Technology

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OUTLINE

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in line with the **Custom Off The Shelf (COTS) philosophy**, we investigate the impact of 60 MeV proton and gamma irradiations on the behavior of NO and RNO deep submicron MOSFETs currently fabricated at IMEC in a 0.13 μ m CMOS technology with STI based isolation.



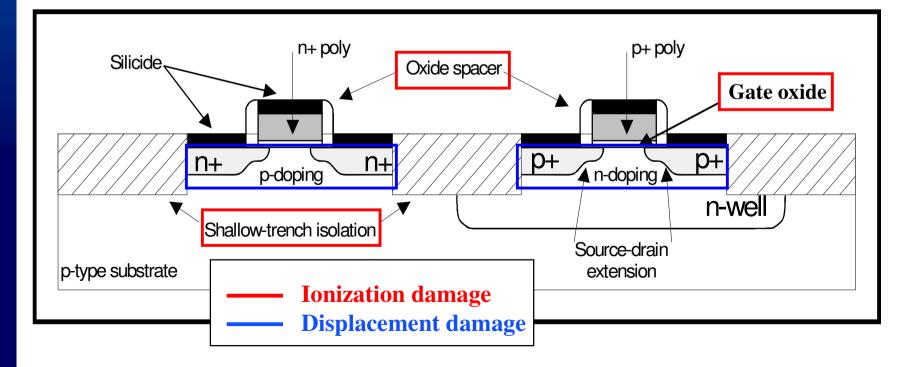
Study of the impact of irradiation **on :**

- Shallow trench isolation
- Gate oxide reliability
- Electrical device parameters



$\textbf{0.13} \; \mu \textbf{m} \; \textbf{CMOS Technology}$

- Shallow trench isolation
- NO and RNO gate oxides
- n+ and p+-doped polysilicon gates (low threshold)
- source-drain extensions LDD (hot-electron effects)
- Self-aligned silicide (spacers)
- Non-uniform channel doping (short-channel effects)





Irradiation matrix

Devices

Two wafers namely wafer 7 (NO) and wafer 9 (RNO) from lot PLINE 9008. Fabricated in a 0.13 µm technology : STI, 2 nm gate oxide, 150 nm polysilicon gate and 80 nm nitride spacers.

W =10 μ m and L = 0.08 μ m till 10 μ m mounted in 24 pins dual-in-line packages for the irradiation under bias (V_G=1.5V)

Pieces of wafer with L-arrays and W-arrays for the irradiation without bias.

Electrical tests conditions

1/ $I_D(V_G)$ measurements for $V_{DS}=25$ mV (ohmic regime) and 1.5 V (saturation regime) 2/ $I_D(V_{DS})$ for different V_G Measurement performed for $V_{BS}=0$ V;

+ Additionnal measurement with $I V_{BS}I=0$ to 1V

+ 1/f noise, gated diode, HF CV



Irradiation matrix

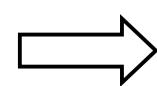
Irradiation conditions

Unbiased and biased (V_G =1.5V) 60 MeV proton and gamma irradiations were performed at the Cyclone cyclotron facility (Louvain-la-Neuve).

Proton : Two fluences typical for space applications, i.e., 10^{11} and 5.10^{11} p/cm⁻². The flux was 3.10^{8} p/cm⁻²s.

 γ : Total dose of 100 krad(Si) and 13.5 krad(Si). The dose rate was 5 krad(Si)/hr.

Conditions were chosen to be approximately equivalent in terms of total dose



separating the role of ionization damage from displacement damage.



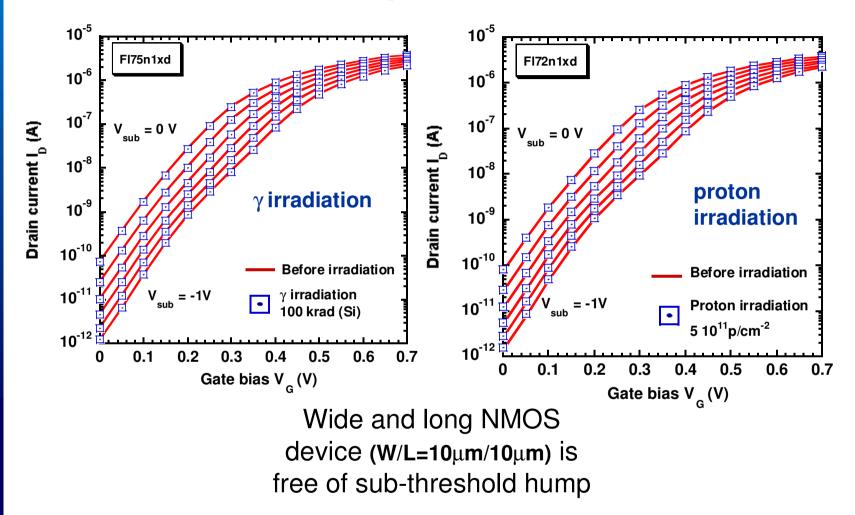
Shallow trench isolation **STI edge effects** Edge parasitic device in n-MOSFETs: 4 10⁻¹ Poly gate NCE Σ p-MOSFETs Gate oxide Threshold voltage I V_1 E E 3 10⁻¹ STI STI oxide n-MOSFETs oxide **STI corner 2 10**⁻¹ with lower V_T **RNCE** Wafer 9 (1/2/3) RNO p,n-MOS w-array Channel width W 1 10⁻¹ 0.1 10 sub-threshold «hump» Channel width W (µm) $log(I_D)$ Wide and long off-current NMOS devices can increase ! show this subthreshold hump V_G

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No Subthreshold "hump" in IMEC STI module

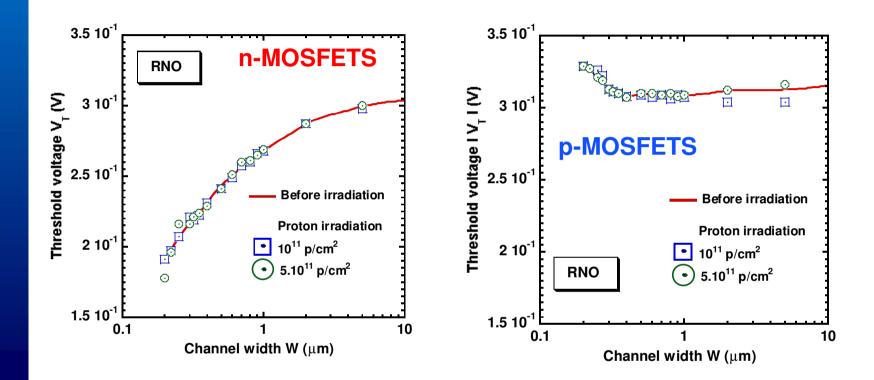


No strong sub-threshold hump observed in IMEC STI module for n-MOS devices at high (negative) substrate bias after irradiation

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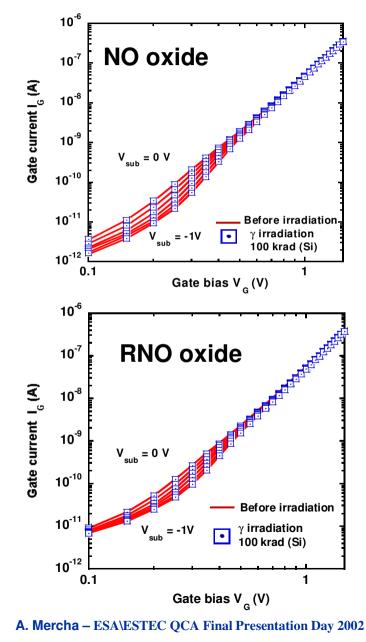
Threshold voltage of W-arrays do not show evidence for radiation induced degradation

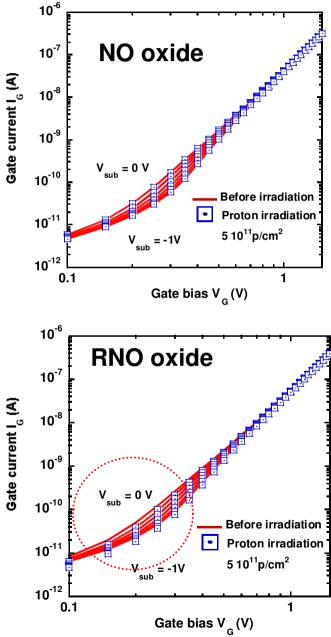


IMEC STI module is a good candidate for integration in hard technology until a total dose of 100 krads



Gate current do not show evidence for radiation induced degradation

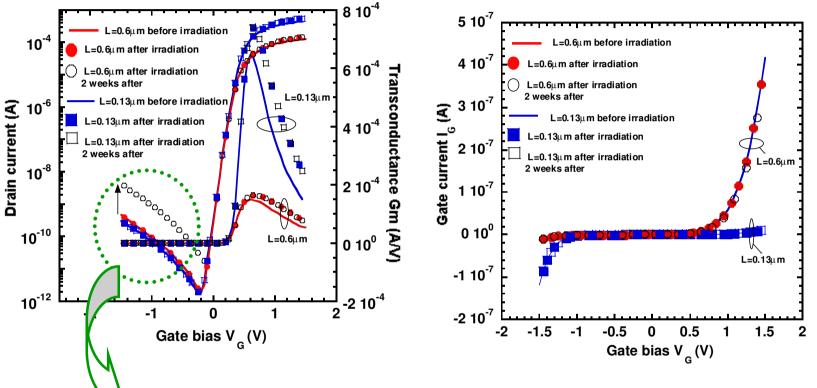




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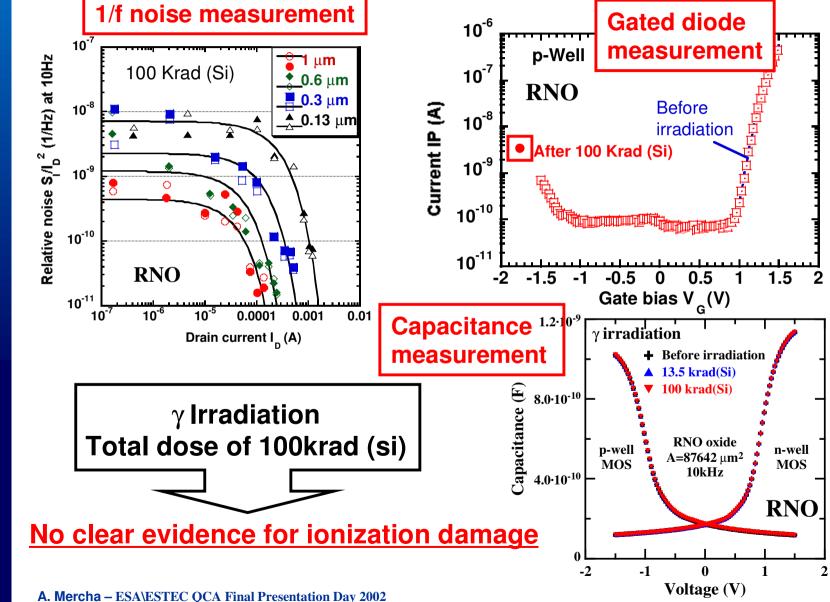
The subthreshold slope do not show evidence for interface or oxide degradation



After some time gate induced drain leakage can appear

But the rest of the characteristic remains unchanged

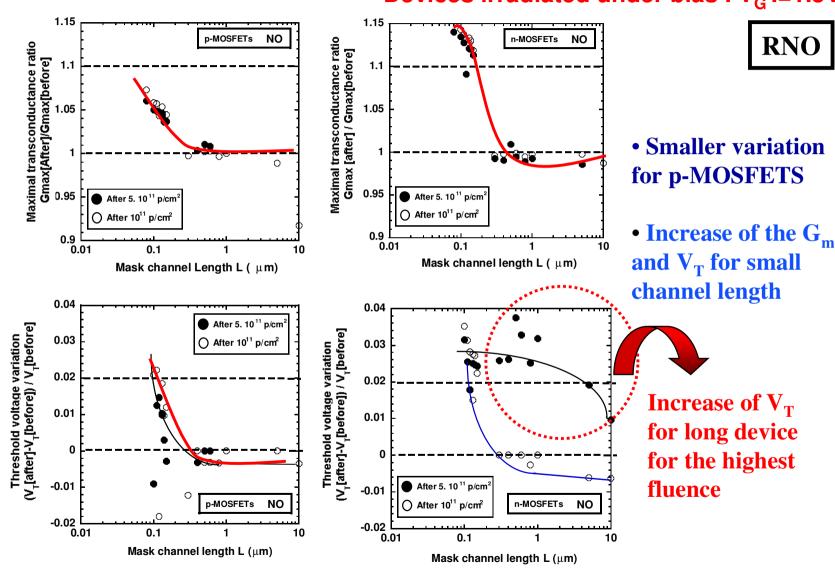
Other techniques to assess the oxide and interface degradation



imec



Irradiation impact on electrical parameters





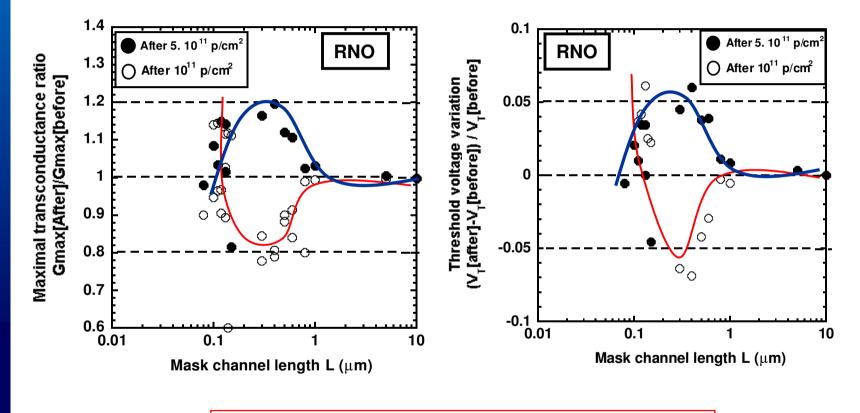
Irradiation impact on electrical parameters

1.15 1.2 NO p-MOSFETs RNO Maximal transconductance ratio Gmax [after] / Gmax[before] n-MOSFETs RNO Maximal transconductance ratio Gmax [after] / Gmax[before] 1.1 1.15 1.1 1.05 • No variation for p-1.05 and n- MOSFETs at ്ത 10¹¹p/cm² 0.95 After 5. 10¹¹ p/cm² After 5. 10¹¹ p/cm 0.95 After 10¹¹ p/cm² ∩ After 10¹¹ p/cm² 0.9 0.01 0.1 • Increase of the G_m 10 1 0.9 10 0.01 0.1 1 Mask channel length L (µm) Mask channel length L (µm) V_T for and small channel length at 5 0.08 0.08 •8 10¹¹p/cm² After 5, 10¹¹ p/cm³ After 5. 10¹¹ p/cm Threshold voltage variation (V_T [after]- V_T [before] Threshold voltage variation $(V_T [after] - V_T [before]) / V_T [before]$ 0.06 0.06 () After 10¹¹ p/cm² O After 10¹¹ p/cm² 0.04 0.04 0.02 0.02 Reduction of V_T 0 ୍ବରଞ୍ଚ 0 for long device -0.02 -0.02 p-MOSFETs RNC n-MOSFETs RNO for the highest -0.04 -0.04 0.01 0.1 1 10 0.1 0.01 1 10 fluence Mask channel length L (µm) Mask channel length L (µm)



Irradiation impact on electrical parameters

Devices irradiated without bias

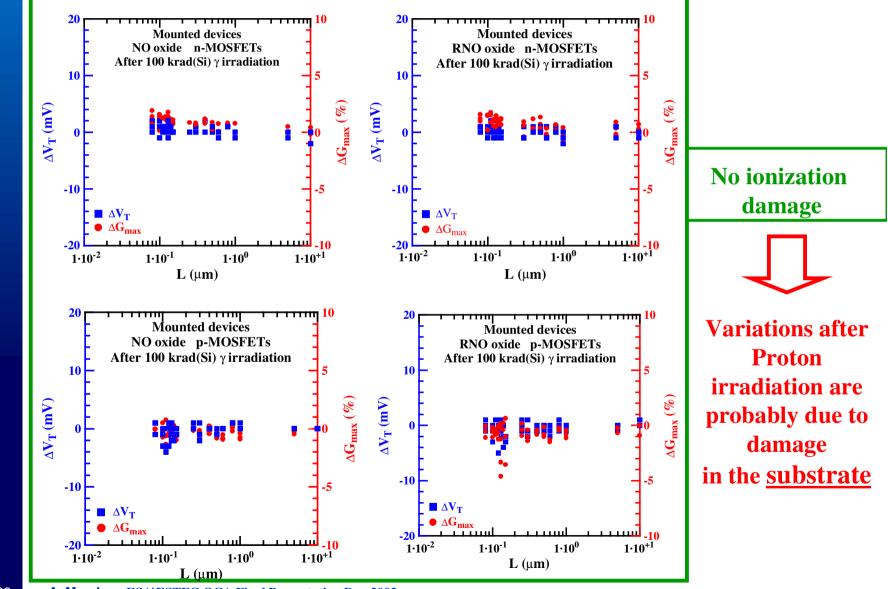


A rebound behavior for both V_T and G_m

The rebound sign seems to depend on the fluence ?



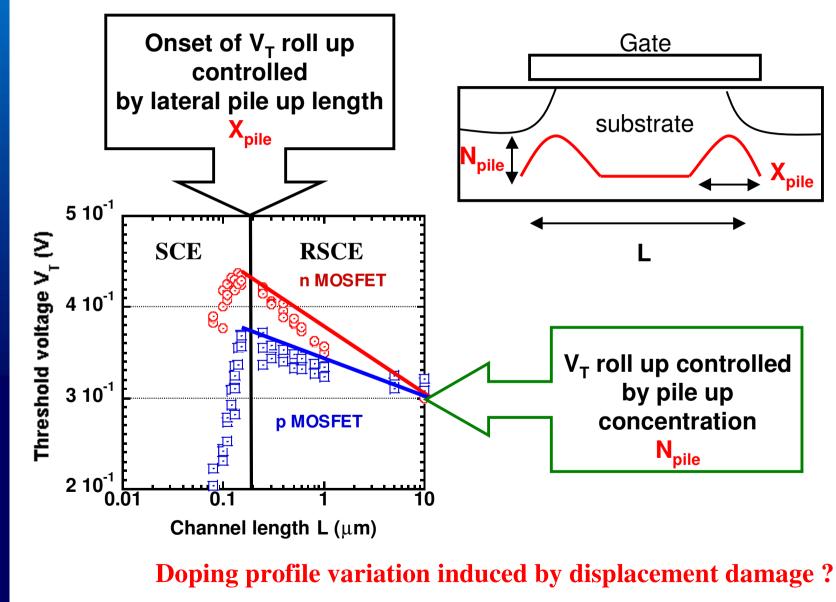
100Krads γ irradiated under bias devices do not show significant variations



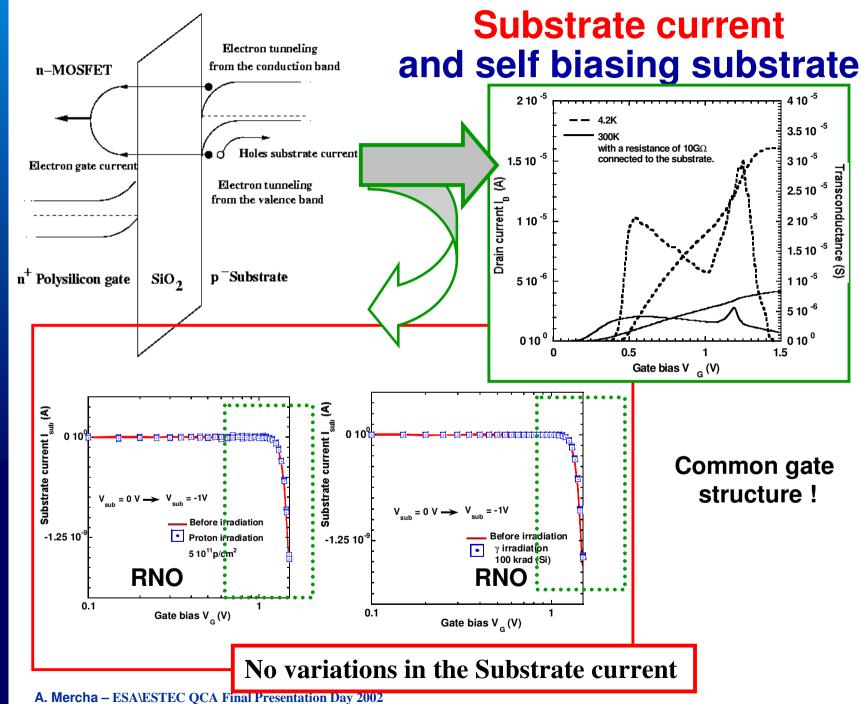
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Doping profile and Reverse Short Channel Effect









Conclusions

- This scaled technology can withstand proton and gamma space irradiation
- I-V, C-V and noise measurements show no substantial degradation of the STI and the gate oxide for <u>IMEC technology</u>
- The transconductance increases for short channel n-MOSFETs irradiated under bias
- The variations of $G_m\,$ an V_T of n-MOSFETs irradiated without bias show complex rebound behavior

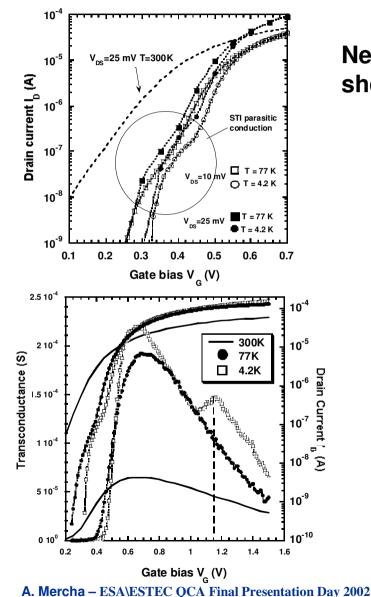
These small variations could be related to substrate damage and specific to the common gate test structure ?

Devices from **IMEC 0.13** µm technology are radiation hard

But need for experimental results on circuits level (SEU ?)



Perspectives : Low temperature irradiation



Next low temperature irradiation matrix should give insights on

- 1/ STI degradation
- 2/ Substrate degradation

At low temperature (4.2K) the substrate freeze out can induce a substrate self bias